Patent

Atty. Docket: H37-116 US

ABSTRACT

Workpiece with at least one functional face and a layer system deposited on at least

a portion of the functional face as well as a structure pattern, which encompasses at least

a portion of the layer system and which is comprised of at least one three dimensional

micro structure (5) with structure depth S, characterized in that the deposited layer system

is deposited with PVD, CVD or combined PCD/CVD processes, and the three dimensional

micro structure (5) extends from the surface of the layer system (4) up into the workpiece,

such that the latter is uncoated in a lower region of the micro structure (5).

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IN THE ABSTRACT:

Please include the Abstract of the Disclosure, which is attached hereto on a separate sheet.